

[View Sale Catalog](#)
[Rigger checkout procedure](#)
[View Letter of Guarantee](#)
[View Proxy Bid Form](#)
[View Agent Release Form](#)
[View State Sales Tax Forms](#)
[View Terms and Conditions](#)

Starting: February 28, 2012 - 3:00 pm EST

Ending: February 29, 2012 - 6:00 pm EST

On Behalf Of: TechnoCorp Energy LLC

Location: 339 East Avenue Suite 4320 Rochester, NY
14604-2615 USA

Inspection: by Appointment only, please contact
Dweiss@hgpauction.com

Lot 1

[SSEC M3306 Manual](#)

Lot 2

[SSEC M3302 Manual](#)

Key Assets:

1. SSEC M3306 COAT/BAKE/CHILL PROCESSOR - 150mm x 150mm (6") single wafer / substrate wet processing COAT/BAKE/CHILL processor. The system features a 60" Wide x 76" Deep x 95" High Cassette System, Cassette to Cassette Auto Processing, One Dual Blade Robotic Handler for Precision Substrate Handling, One HMDS Vapor Prime Stackable Hot Plate Bake Station; One Stackable Chill Station; One Molded, Resist Coat Processing Module with eight Programmable Dispense Arms; three Precision Hot Plate Bake Stations; two Automatic Programmable Pressure & Flow Control Systems; includes Full PC with Flat Panel Display, Keyboard, Hard Drive, and R/W CD/DVD ROM for Log Files and SSEC Documentation. [Please see attached for Spec sheet](#)

2. SSEC M3302 CLEAN/DEVELOP PROCESSOR - 150mm x 150mm (6") single wafer / substrate wet processing CLEAN/DEVELOP processor. The system features a 60" Wide x 76" Deep x 95" High Cassette System, Cassette to Cassette Auto Processing, One Dual Blade Robotic Handler for Precision Substrate Handling, One molded Clean Processing Chamber with a fully programmable Three Fan Dispense Arm Chemical Delivery System; One molded Develop Processing chamber with a fully programmable Four Fan Dispense Arm Chemical Delivery System; one automatic Rotary Brush Scrubbing System; One High Velocity Spray Scrubbing Dispense System; includes Full PC with Flat Panel Display, Keyboard, Hard Drive, and R/W CD/DVD ROM for Log Files and SSEC Documentation. [Please see attached for Spec sheet](#)

3. ULVAC Beta CVD System - This ULVAC Beta CVD System is an OLED substrate pretreatment processing tool, used for cleaning of ITO surface and deposition of CFx holeinjection layer. The equipment is a two plasma chamber processing tool. It is a custom designed manual tool previously used in the research and development of Kodak's (now LG Chemical's) industry defining Organic Light Emitting Diode (OLED) patent portfolio and technology. [Please see attached for Spec sheet](#)

Contact:

David Weiss

Vice President of Sales

Dweiss@hgpauction.com

561-210-5921



